CLAIMS

What is claimed is:

1. A method for forming a free standing micro-structural member comprising the steps of:

providing a substrate;

forming a first sacrificial resist layer over the substrate;

patterning the first sacrificial resist layer to form a first resist portion;

subjecting the first resist portion to at least a first hard bake process to form the first resist portion having a first volume;

forming at least a second sacrificial resist layer followed by patterning and conducting at least a second hard bake process to form a final resist portion having a final volume; and,

depositing at least one structural material layer over the final resist portion.

- 2. The method of claim 1, wherein the at least a first hard bake process further comprises one of a prior or at least partially simultaneous exposure to polymeric cross-linking inducing radiant energy.
- 3. The method of claim 2, wherein the radiant energy comprises ultraviolet light having a wavelength of less than about 350 nm.
- 4. The method of claim 2, wherein the ultraviolet light further comprises a radiation intensity between 50 mJ/cm 2 and 200 mJ/cm 2 , a radiation temperature between 150 °C and 250 °C, and a radiation time between 10 and 60 minutes.
- 5. The method of claim 2, wherein exposure to the polymeric cross-linking inducing radiant energy is carried out prior to the hard bake step comprising a thermal heating step.
- 6. The method of claim 2, wherein exposure to the polymeric cross-linking inducing radiant energy is carried out at least during a portion of the hard bake process.

- 7. The method of claim 1, wherein the hard bake process comprises a baking temperature of from about 250 °C to about 350 °C.
- 8. The method of claim 1, wherein the first smaller volume is smaller compared to the desired final resist portion volume by about 5 % to about 50 %.
- 9. The method of claim 1, further comprising the step of removing resist comprising the final resist portion according to at least one of an ashing process and a wet stripping process to form a free-standing structural member.
- 10. The method of claim 1, wherein the structural material is selected from the group consisting of metals, nitrides, oxides, carbides, and titanates.
- 11. The method of claim 1, wherein the structural material is selected from the group consisting of metals, metal nitrides, refractory metals, refractory metal nitrides, oxides, carbides, and piezo-electric oxides.

12. A method for forming a free standing micro-structural member comprising the steps of:

providing a substrate;

forming a first sacrificial resist layer over the substrate;

patterning the first sacrificial resist layer to form a first resist portion;

subjecting the first resist portion to at least a first post treatment process to form the first resist portion having a first volume;

forming at least a second sacrificial resist layer followed by patterning and conducting at least a second post treatment process to form a final resist portion having a final volume; and,

depositing at least one structural material layer over the final resist portion.

13. A method for forming a free standing micro-structural member over a resist portion with improved dimensional tolerances comprising the steps of:

providing a substrate;

forming a first resist layer over the substrate;

patterning the first resist layer to form a first resist portion having a predetermined first volume smaller compared to a predetermined final resist portion volume;

subjecting the first resist portion to a first curing process comprising deep UV irradiation and thermal heating for a predetermined period to harden the first resist portion;

forming at least a second resist layer having a predetermined thickness over the first resist portion followed by patterning and a second curing process to form the final resist portion volume;

depositing at least one structural material layer over the final resist portion; and,

removing the final resist portion according to at least one of an ashing and a wet stripping process to form a free standing structural member.

- 14. The method of claim 13, wherein the first and second curing processes comprise exposure to the deep UV irradiation prior to the thermal heating period.
- 15. The method of claim 13, wherein the first and second curing processes comprise exposure to the deep UV irradiation during at least a portion of the thermal heating period.
- 16. The method of claim 13, wherein the thermal heating period comprises a temperature of from about 250 °C to about 350 °C.
- 17. The method of claim 13, wherein the first volume is smaller compared to the final resist portion volume by about 5 % to about 50 %.
- 18. The method of claim 13, wherein the first volume is smaller compared to the final resist portion volume from about 10% to about 33%.

- 19. The method of claim 13, wherein the first smaller volume comprises sidewall portions formed having a smaller dimension by a factor of about 1/2 compared to a smaller thickness dimension.
- 20. The method of claim 13, wherein the structural material is selected from the group consisting of metals, metal nitrides, refractory metals, refractory metal nitrides, oxides, carbides, and metal titanates.